

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)

 ATTY. DOCKET NO.
60188-654

SERIAL NO.

101661,542

 APPLICANT
Masayuki ENDO, et al.

 FILING DATE
September 15, 2003

 GROUP
1756

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			
		US			

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes -Number -Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
					class/sub	Yes	No
KUD	A	JP P2001-316863	11/16/2001	TDK CORP	— —	(Japan w/English Abstract)	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
KUD		M. Swilkes et al., "Immersion lithography at 157 nm", J. Vac. Sci. Technolo., B19, 2353 (2001)

EXAMINER

K. Duda

DATE CONSIDERED

11-28-05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.